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| Substitute for form 1449B/PTO | | Complete if Known | |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary) | | Application Number | Not yet assigned - 12825200 |
| | | Filing Date | On even date herewith 4/14/04 |
| | | First Named Inventor | Darrin Leonhardt |
| | | Group Art Unit | Not yet assigned - 1753 |
| | | Examiner Name | Not yet assigned - VerSteg |
| | | Attorney Docket Number | 95,876 |
| Sheet 2 | of 2 | | |

| OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS | | | |
|---|-----------|---|----|
| Examiner Initials* | Cite No.† | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T‡ |
| SHV | | U.S. Patent Application 10/644,567 entitled "Electron Beam Enhanced Large Area Deposition System" filed on August 20, 2003 by Scott G. Walton et al. | |
| SHV | | U.S. Patent Application 10/672,269 entitled "Method and Apparatus for Producing an Ion-Ion Plasma Continuous in Time" filed on September 26, 2003 by Richard F. Fernsler et al. | |
| SHV | | R. F. FERNSLER ET AL., "Production of large-area plasmas by electron beams," Phys. Plasmas, 1998, 5, 2137-2143 | |
| SHV | | WALLACE M. MANHEIMER ET AL., "Theoretical overview of the large-area plasma processing system (LAPPS)," Plasma Sources Sci. Technol. 2000, 9, 370-386 | |
| SHV | | S. G. WALTON ET AL., "Ion energy distributions in a pulsed, electron beam-generated plasma," J. Vac. Sci. Technol. A, 2001, 19(4), 1325-1329 | |
| SHV | | D. LEONHARDT ET AL., "Plasma diagnostics in large area plasma processing system," J. Vac. Sci. Technol. A, 2001, 19(4), 1367-1373 | |
| SHV | | R. A. MEGER ET AL., "Beam-generated plasmas for processing applications," Phys Plasmas, 2001, 8, 2558-2564 | |
| SHV | | DARRIN LEONHARDT, "Electron-Beam Produced Plasmas: Considerations and Applications," Vacuum Technology & Coating, November 2001, 24-35 | |
| SHV | | D. LEONHARDT ET AL., "Generation of electron-beam produced plasmas and applications to surface modification," Surface and Coatings Technology, 2004, 177-178, 682-687 | |
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| Examiner Signature |  | Date Considered | August 9, 2005 |
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

† Unique citation designation number. ‡ Applicant is to place a check mark here if English language Translation is attached.

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